

Bongsang Kim

List of Publications by Year in descending order

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29
papers

1,526
citations

687220

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794469

19
g-index

29
all docs

29
docs citations

29
times ranked

837
citing authors

#	ARTICLE	IF	CITATIONS
1	MEMS Packaging. , 2016, , 2019-2028.		1
2	Oven-Based Thermally Tunable Aluminum Nitride Microresonators. Journal of Microelectromechanical Systems, 2013, 22, 265-275.	1.7	12
3	The effect of the temperature-dependent nonlinearities on the temperature stability of micromechanical resonators. Journal of Applied Physics, 2013, 114, 153513.	1.1	9
4	Electrostatic Tuning to Achieve Higher Stability Microelectromechanical Composite Resonators. Journal of Microelectromechanical Systems, 2011, 20, 1355-1365.	1.7	13
5	AC Polarization for Charge-Drift Elimination in Resonant Electrostatic MEMS and Oscillators. Journal of Microelectromechanical Systems, 2011, 20, 355-364.	1.7	16
6	Influence of the temperature dependent nonlinearities on the performance of micromechanical resonators. Applied Physics Letters, 2011, 99, .	1.5	7
7	Model and Observations of Dielectric Charge in Thermally Oxidized Silicon Resonators. Journal of Microelectromechanical Systems, 2010, 19, 162-174.	1.7	37
8	Influence of the temperature dependent A-f effect on the design and performance of oscillators. , 2010, , .		1
9	Ovenized and thermally tunable aluminum nitride microresonators. , 2010, , .		25
10	Hermeticity and diffusion investigation in polysilicon film encapsulation for microelectromechanical systems. Journal of Applied Physics, 2009, 105, .	1.1	25
11	Temperature-Insensitive Composite Micromechanical Resonators. Journal of Microelectromechanical Systems, 2009, 18, 1409-1419.	1.7	202
12	A study of electrostatic force nonlinearities in resonant microstructures. Applied Physics Letters, 2008, 92, .	1.5	45
13	Temperature Dependence of Quality Factor in MEMS Resonators. Journal of Microelectromechanical Systems, 2008, 17, 755-766.	1.7	208
14	Thermal Isolation of Encapsulated MEMS Resonators. Journal of Microelectromechanical Systems, 2008, 17, 175-184.	1.7	67
15	Identification and management of diffusion pathways in polysilicon encapsulation for MEMS devices. Proceedings of the IEEE International Conference on Micro Electro Mechanical Systems (MEMS), 2008, , .	0.0	6
16	Si-SiO2 Composite MEMS Resonators in CMOS Compatible Wafer-scale Thin-Film Encapsulation. , 2007, , .		15
17	Temperature-compensated high-stability silicon resonators. Applied Physics Letters, 2007, 90, 244107.	1.5	109
18	Scaling of amplitude-frequency-dependence nonlinearities in electrostatically transduced microresonators. Journal of Applied Physics, 2007, 102, .	1.1	52

#	ARTICLE	IF	CITATIONS
19	Composite flexural-mode resonator with controllable turnover temperature. , 2007, , .		33
20	Acceleration sensitivity in beam-type electrostatic microresonators. Applied Physics Letters, 2007, 90, 014103.	1.5	8
21	Frequency stability of wafer-scale film encapsulated silicon based MEMS resonators. Sensors and Actuators A: Physical, 2007, 136, 125-131.	2.0	114
22	Long-Term and Accelerated Life Testing of a Novel Single-Wafer Vacuum Encapsulation for MEMS Resonators. Journal of Microelectromechanical Systems, 2006, 15, 1446-1456.	1.7	183
23	Nonlinear Characterization of Electrostatic MEMS Resonators. , 2006, , .		27
24	Impact of Geometry on Thermoelastic Dissipation in Micromechanical Resonant Beams. Journal of Microelectromechanical Systems, 2006, 15, 927-934.	1.7	127
25	Optimal drive condition for nonlinearity reduction in electrostatic microresonators. Applied Physics Letters, 2006, 89, 214105.	1.5	60
26	Hydrogen diffusion and pressure control of encapsulated MEMS resonators. , 0, , .		23
27	Frequency stability of wafer-scale encapsulated MEMS resonators. , 0, , .		60
28	Impact of slot location on thermoelastic dissipation in micromechanical resonators. , 0, , .		4
29	Effects of stress on the temperature coefficient of frequency in double clamped resonators. , 0, , .		37